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LIST OF SYMBOLS AND ABBREVIATIONS

SYMBOLS

V	Applied voltage
$\Delta\lambda$	Change in wavelength
C_i	Contour intensity
δ	Deflection depth of the active ribbon
$\delta (V_{avg})$	Deflection in biasing ribbon due to fringe voltage
$ F $	Driving force
δ_{eff}	Effective deflection of the active ribbon
ϵ	Effective permittivity
E	Energy stored in the capacitor
$\eta_{\pm 1}$	First order diffraction efficiency
I_{st}	First order Intensity
I_{max}	First order maximum Intensity
ϵ_0	Free space permittivity
V_{avg}	Fringe voltage
g	Gap between the neighbouring ribbon.
h	Gap between the top and bottom electrode
R_g	Gap reflectivity
n_H	High refractive index
δ_{ideal}	Ideal deflection of the active ribbon
n_L	Low refractive index
N	Number of layers
m	Order of diffraction
Λ	Period between the deflected beams

θ_m	Phase offset between the wave fronts
α	Propagation constant
ϵ_r	Relative permittivity
A	Ribbon area
L	Ribbon length
R_r	Ribbon reflectivity
t	Ribbon thickness
W	Ribbon width
n_s	Substrate refractive index
V_s	Threshold voltage
λ	Wave length of light
η_0	Zeroth order diffraction efficiency

ABBREVIATIONS

ASIMS	Application Specific Integrated Microsystems
BEM	Boundary Element Method
CAD	Computer Aided Design
CMDM	Continues Membrane Deformable Mirror
CTP	Computer To Plate
DDE	Digital Display Engine
DFM	Design For Manufacturability
DLP	Digital Light Processing
DMD	Digital Micro-Mirror Device
DWDM	Dense Wavelength Division Multiplexing
FEM	Finite Element Method
GLV	Grating Light Valve
HDL	Hardware Description Language
HDTV	High Definition Television

HUD	Heads Up Display
LCD	Liquid Crystal Display
LED	Light Emitting Diode
MEMS	Micro Electro Mechanical Systems
MM	Micro Machines
MOEMS	Micro Opto Electro Mechanical Systems
MST	Micro Systems Technology
OADM	Optical ADD/Drop Multiplexer
OEO	Optical Electronic optic
SGA	Scanned GLV Architecture
Si DRIE	Silicon Deep Reactive Ion- Etching
TI	Texas Instruments
TMA	Thin Film Micromirror Array
TMOS	Transmissive Micro-Optics Switches
VCSEL	Vertical Cavity Surface Emitting Laser
VOA	Variable Optical Attenuator